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## AMENDMENTS TO THE SPECIFICATION

Please amend paragraphs [0029] and [0030] of the specification as published as follows:

[0029] The first reactant **28** will be a compound having the elements of the monolayer to be formed on the part **12** such as the first reactants listed below in Examples 1-7. The first reactant **28** is introduced into the reactor vessel **2** through solenoid operated pneumatic valve **20** by a manifold **18**. **FIG. 1** illustrates a system with two bottles **30** and **31**, each containing a first reactant **28** and **29** and having temperature controllers 32 and 33, however, the type of film to be formed will determine the number of reactants and bottles. For example, if a ternary film is desired, the system will include three bottles and three valves. A conventional digital microcontroller **40** sequences the opening and closing of the valves **20** and **22** to deliver the first reactants to the chamber at the appropriate times as illustrated in **FIG. 2**.

[0030] Referring to **FIG. 1**, during a typical operation, a monolayer of the first reactant is deposited on the part **12** to be coated by exposure to the first reactant **28** in vapor phase from the bottle **30**. This monolayer is reacted by exposing it to a flux of radicals generated by the action of a solenoidal coil **14**, excited by a RF power supply **16**, on molecules introduced from a gas bottle **34** through valve 24. The RF power supply **16** can be controlled by the microcontroller circuit **40**.